



Docket No.: 291958163US2  
Client Ref No. P99-0016US3

(PATENT)

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re Patent Application of:  
Linlin Chen

Allowed: June 16, 2004

Application No.: 09/885,232

Confirmation No.: 4989

Filed: June 20, 2001

Art Unit: 1742

For: APPARATUS AND METHOD FOR  
ELECTROLYTICALLY DEPOSITING  
COPPER ON A SEMICONDUCTOR  
WORKPIECE

Examiner: W. A. Nicolas

**COMMENTS ON STATEMENT OF REASONS  
FOR ALLOWANCE UNDER 37 CFR §1.104(E)**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

Applicant has received the Examiner's Statement of Reasons for Allowance with the June 16, 2004 Notices of Allowance and Allowability regarding the above-identified application. Entry of the Statement into the record should not be construed as any agreement with or acquiescence in the reasoning stated by the Examiner. Each of the claims stands on its own merits and is patentable because of the combination it recites and not because of the presence or absence of any one particular element.

The Examiner's Statement was not prepared by Applicant and only contains the Examiner's possible positions in one or more reasons for allowability. Thus, any interpretation with respect to the Examiner's Statement of Reasons for Allowance should not be imputed to the Applicant.

Applicant believes no fee is due with this response. However, if a fee is due, please charge our Deposit Account No. 50-0665, under Order No. 291958163US2 from which the undersigned is authorized to draw.

Dated: 15 Sept 84

Respectfully submitted,

By

  
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